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July 20, 2004

Mail Stop Amendment
 Commissioner For Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

Re: Applicant(s): George D. Papasoullotis; Bart van Schravendijk; Robert D. Tas;
 Patrick A. Van Cleemput
 Assignee: Novellus Systems, Inc.
 Title: Process for Depositing F-Doped Silica Glass in High
 Aspect Ratio Structures
 Serial No.: 10/035,773
 Examiner: Julian A. Mercado
 Docket No.: M-5091-2P US
 Filed: December 21, 2001
 Group Art Unit: 1745

Dear Sir:

Transmitted herewith are the following documents in the above-identified application:

- (1) This Transmittal Letter;
- (2) Response to Office Action (9 pages); and
- (3) Terminal Disclaimer to Obviate a Double Patenting Rejection Over a Patent.

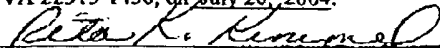
CLAIMS AS AMENDED

	Claims Remaining After Amendment		Highest No. Previously Paid For		Present Extra	Rate	Additional Fee
Total Claims	35	Minus	35	=	0	x \$18.00	\$ 0
Ind. Claims	3	Minus	3	=	0	x \$84.00	\$ 0
<input checked="" type="checkbox"/> Fee Code 1814, Statutory Disclaimer							\$ 110.00

Please make the following charges to Deposit Account No. 50-2257

- ☒ The Commissioner is hereby authorized to charge Deposit Account No. 50-2257. \$ 110.00
☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-2257.

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope or Facsimile transmitted, addressed to: Commissioner for Patents, Alexandria, VA 22313-1450, on July 20, 2004.


 Rita K. Kimmel

Respectfully submitted,



Tom Chen
 Attorney for Applicant(s)
 Reg. No. 42,406